



EP 1741 /
PATENT

#4
Ref
10-22-02

Case Docket No. SEPP16.001AUS

Date: October 8, 2002

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Aaltonen et al.)
Appl. No. : 10/066,315)
Filed : January 29, 2002)
For : PROCESS FOR PRODUCING)
METAL THIN FILMS BY ALD)
Examiner : Unknown)
Group Art Unit : 1741)

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October 8, 2002

(Date)

Adeel Syed Akhtar
Adeel S. Akhtar, Reg. No. 41,394

TRANSMITTAL LETTER

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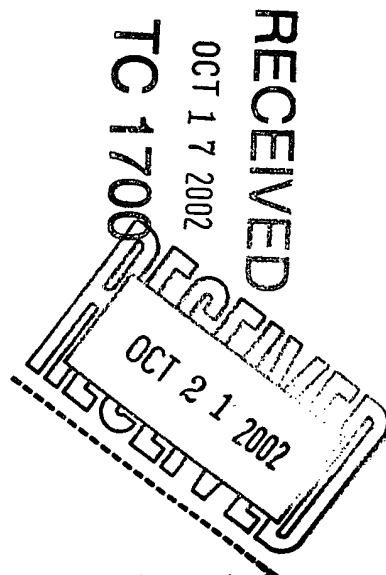
ATTENTION: APPLICATION BRANCH

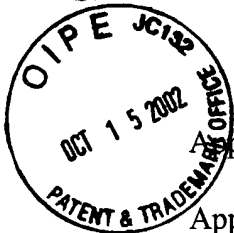
Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 with five (5) references.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.

Adeel Syed Akhtar
Adeel S. Akhtar
Registration No. 41,394
Attorney of Record





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INFORMATION DISCLOSURE STATEMENT

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Dear Sir:

Enclosed is form PTO-1449 listing 5 references that are also enclosed. This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: October 8, 2002

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FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
SEPP16.001AUSAPPLICATION NO.
10/066,315INFORMATION DISCLOSURE STATEMENT
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT
Aaltonen et al.FILING DATE
January 29, 2002GROUP
1741

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1.	U.S. 5,916,365	6/29/99	Arthur Sherman			
	2.	U.S. 6,342,277 B1	1/29/02	Arthur Sherman			

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)						
	3.	Fullerton et al., <u>Solid State Technology</u> , September 2001 v44 i9 p87					
	4.	M. Ritala and M. Leskela, Atomic Layer Deposition, in <u>Handbook of Thin Film Materials Vol. 1: Deposition and Processing of Thin Films</u> , Ed. H.S. Nalwa, Academic Press, San Diego (2001) Table of Contents (pp. xi - xviii), Chapter 2, p. 103.					
	5.	Aoyama et al., "Chemical Vapor Deposition of Ru and Its Application in (Ba, Sr) TiO ₃ Capacitors for Future Dynamic Random Access Memories", <u>Jpn. J. Appl. Phys. Vol. 38 (1999) Part I No. 43</u> , pp. 2194-2199.					

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